

Substitute for form 1449/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (Use as many sheets as necessary)				<b>Complete if Known</b>	
				Application Number	10/817,398
				Filing Date	April 1, 2004
				First Named Inventor	KOROLIK et al.
				Art Unit	1746
				Examiner Name	Unassigned
Sheet	2	of	4	Attorney Docket Number	LAM2P467

## U.S. Patent Documents

Examiner Initials	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
/JH/	A	2005/0217703	10/06/05	O'Donnell	
/JH/	B	2006/0064895	03/30/06	Garcia et al.	
/JH/	C	3,953,265	04/27/76	Hood	
/JH/	D	<del>4,637,123</del> 4,367,123	01/04/83	Beck	
/JH/	E	4,444,492	04/24/84	Lee	
/JH/	F	4,838,289	06/13/89	Kottman et al.	
/JH/	G	5,102,494	04/07/92	Harvey et al.	
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/JH/	L	5,472,502	12/05/95	Batchelder	
/JH/	M	5,558,111	09/24/96	Lofaro	

## Foreign Patent Documents

Examiner Initial	Cite No. <sup>1</sup>	Foreign Patent Document No.	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
		Country Code <sup>3</sup> -Number <sup>4</sup> -Kind Code <sup>5</sup> (if known)				
/JH/	N	JP11031672 (Patent Abstract in English provided)	02/02/99	Hitachi Ltd.		
/JH/	O	JP62150828 A (Patent Abstract in English provided)	07/04/87	Mitsubishi Electric Corporation		<input type="checkbox"/>

## Non Patent Literature Documents

Examiner Initial	Cite No.	Include name of author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published
/JH/	P	"Chemical vapor deposition", Wikipedia, the free encyclopedia, <a href="http://en.wikipedia.org/wiki/Chemical_vapor_deposition">http://en.wikipedia.org/wiki/Chemical_vapor_deposition</a> , 2005, Page 1-2
/JH/	Q	OWA et al. "Immersion lithography; its potential performance and issues", Proceedings of the SPIE, SPIE, Bellingham, VA, US, Vol. 5040, No. 1, February 28, 2003, pages 724-733, XP002294500

Examiner Signature	/Jason Heckert/	Date Considered	03/23/2007
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		Number-Kind Code <sup>2</sup> (if known)			
/JH/	A	2003/0091754	05/15/03	Chihani et al.	
/JH/	B	2003/0092264	05/15/03	<del>Shinji et al.</del> Kajita et al.	
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/JH/	H	2005/0132515	06/2005 <del>12/18/03</del>	Boyd et al.	
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		Country Code <sup>3</sup> -Number- <sup>4</sup> Kind Code <sup>5</sup> (if known)				
/JH/	N	EP 1 489 461 A1	12/22/04	ASML Netherlands B.V.		<input type="checkbox"/>
/JH/	O	EP 1 489 462 A2	12/22/04	ASML Holding N.V.		<input type="checkbox"/>

## Non Patent Literature Documents

Examiner Initial	Cite No.	Include name of author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published
/JH/	P	LIM et al., "Atomic Layer deposition of transition metals", Department of Chemistry and Chemical Biology, Harvard University, Nature Publishing Group, Volume 2, November 2003, Pages 749-754
/JH/	Q	ICKnowledge LLC, "Technology Backgrounder: Atomic Layer Deposition", ICKnowledge.com, 2004, Pages 1-7

Examiner Signature	/Jason Heckert/	Date Considered	03/23/2007
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